



INFORMATION DISCLOSURE STATEMENT BY APPLICANT PTO-1449	DOCKET NO. 10020/29701	SERIAL NO. 10/690,704
	APPLICANT SHTEIN et al.	
	FILING DATE October 23, 2003	GROUP 1762

U. S. PATENT DOCUMENTS

EXAMINER INITIAL	PATENT NUMBER	PATENT DATE	NAME	CLASS	SUBCLASS	FILING DATE
	5,707,745	January 13, 1998	Forrest et al.			
	6,048,630	April 11, 2000	Burrows et al.			
	6,337,102	January 8, 2002	Forrest et al.			
	6,716,656	April 6, 2004	Shtein et al.			
	6,066,357	May 23, 2000	Tang et al.			
	6,165,554	December 26, 2000	Halpern et al.			
	5,356,673	October 18, 1994	Schmitt et al.			
	5,650,197	July 22, 1997	Halpern, Bret			
	5,720,821	February 24, 1998	Halpern, Bret			
	5,759,634	June 2, 1998	Zang, Jian-Zhi			
	10/233,470	September 4, 2002	Shtein et al.			

FOREIGN PATENT DOCUMENTS

EXAMINER INITIAL	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
						YES	NO
	EP 0 173 715	4/22/92	EP				
	WO 01/61071	8/23/01	WO				
	GB 2 336 553	10/27/99	GB				

OTHER DOCUMENTS

EXAMINER INITIAL	AUTHOR, TITLE, DATE, PERTINENT PAGES, ETC.
	ASTM, Compilation of ASTM Standard Definitions, Eighth Edition, p.380 (1994)
	Baldo, et al., "Low pressure organic vapor phase deposition of small molecular weight organic light emitting device structures", <i>Appl. Phys. Lett.</i> 71(21), pp. 3033-3035 (24 November 1997).
	Baldo, et al., "Organic Vapor Phase Deposition", <i>Adv. Mater.</i> 10, No. 18, pp. 1505-1514 (1998)
	Bird, et al., <i>Transport Phenomena</i> , New York, John Wiley & Sons, Inc., pp. 508-513 (1960).
	Burrows, et al., "Organic Vapor Phase Deposition: a new method for the growth of organic



EXAMINER - INITIAL	AUTHOR, TITLE, DATE, PERTINENT PAGES, ETC.
	thin films with large optical non-linearities", <i>J. Cryst. Growth</i> 156, pp. 91-98 (1995).
	Forrest et al., "Intense Second Harmonic Generation and Long-Range Structural Ordering in Thin Films of Organic Salt Grown by Organic Vapor Phase Deposition," <i>Appl. Phys. Lett.</i> , Vol. 68, pp. 1326-1328 (1996)
	Forrest, "Ultrathin Organic films grown by organic molecular beam deposition and related techniques", <i>Chem. Rev.</i> Vol. 97, No. 6, pp. 1793-1896 (September/October 1997).
	Krumdieck, "Kinetic Model of Low Pressure Film Deposition From Single Precursor Vapor in a Well-Mixed, Cold-Wall Reactor", <i>Acta mater.</i> 49, 2001, pp. 583-588.
	Olsen, "Vapour-phase Epitaxy of GaInAsP", <i>GaInAsP Alloy Semiconductors</i> , edited by T. P. Pearsall (Wiley, New York, 1982), pp. 11-41.
	Parker, ed., McGraw-Hill Dictionary of Scientific and Technical Terms, Fifth Edition, p.1516 (1994)
	Shtein et al., "Micropatterning of small molecular weight organic semiconductor thin films using organic vapor phase deposition", <i>J. Appl. Phys.</i> , Volume 93, Number 7, pp. 4005-4016, April 1, 2003.
	Shtein et al., "Effects of Film Morphology and Gate Dielectric Surface Preparation on the Electrical Characteristics of Organic Vapor Phase Deposited Pentacene Thin-Film Transistors," <i>Appl. Phys. Lett.</i> , Vol 81, pp. 268-270 (2002)
	Shtein, et al., "Micron scale patterning of organic thin films via organic vapor phase deposition", Presentation Outline from the Mat. Res. Soc. Ann. Meeting 2001, Boston.
	Shtein, et al., "Material transport regimes and mechanisms for growth of molecular organic thin films using low-pressure organic vapor phase deposition", <i>J. Appl. Phys.</i> 89:2, pp. 1470-1476 (15 January 2001).
	Stringfellow, <i>Organometallic Vapor-Phase Epitaxy: Theory and Practice</i> , pp. 55-283 (Academic, London, 1989).
	Supplementary European Search Report from EP 0 277 0461 dated June 12, 2007
	Vaeth, et al., "Chemical vapor deposition of poly (p-phenylene vinylene) based light emitting diodes with low turn-on voltages", <i>Appl. Phys. Lett.</i> 71 (15), pp. 2091-2093 (13 October 1997).
	Wolf and R. N. Tauber, <i>Silicon Processing for the VLSI Era, Volume1: Process Technology</i> , pp. 73-123 (Lattice, 1986).
	Zhang et al., "Jet Vapor Deposition of Nanostructure Composite Materials", <i>Materials Res. Soc. Symp. Proc.</i> , Mater. Res. Soc. Symposium Proc. 1193, 286, pp. 385-389

EXAMINER /David Turocy/	DATE CONSIDERED 04/08/2008
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